

Supporting Information for

Free-standing Bi-Sb-Te films derived from a thermal annealing of sputter-deposited $\text{Sb}_2\text{Te}_3/\text{Bi}_2\text{Te}_3$ multilayer films for thermoelectric applications

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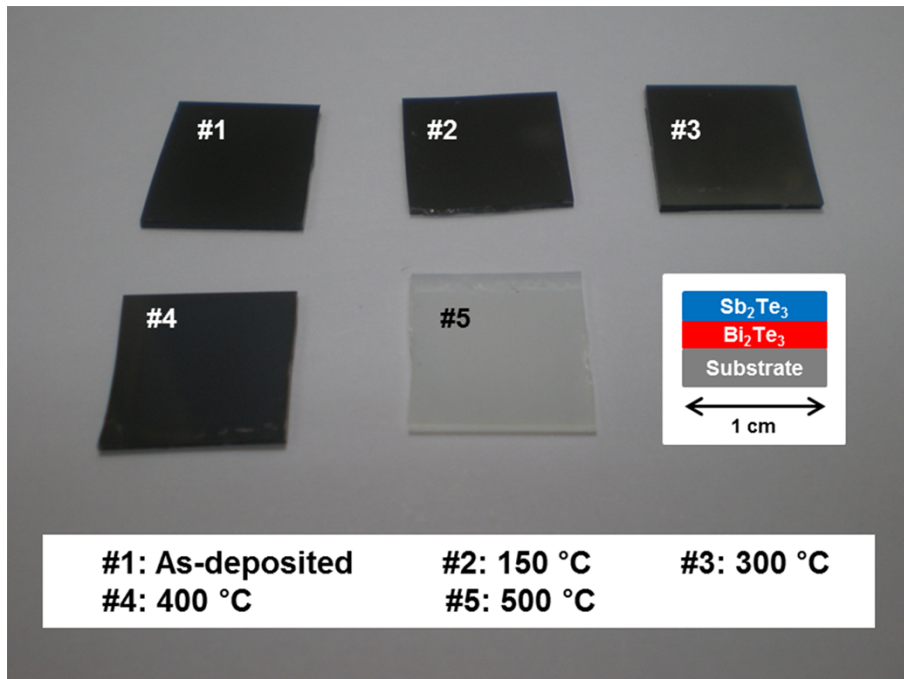


Fig. S1. Photograph of Bi₂Te₃/Sb₂Te₃ multilayer films as a function of annealing temperature.

Inset shows a cross-section of samples.